

Form PTO-1449 (MODIFIED)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. 039153-0405 (80945)		SERIAL NO. 09/820,143		
INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)				APPLICANT Uzodinma Okoranyanwu et al.				
				FILING DATE 03/28/2001		GROUP ART UNIT 2878		
U.S. PATENT DOCUMENTS								
EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB- CLASS	FILING DATE IF APPROPRIATE	
ME		09/819,342		Shields et al			03/28/01	
ME		09/819,343		Gabriel et al			03/28/01	
ME		09/819,344		Okoroanyanwu et al			03/28/01	
ME		09/819,552		Gabriel et al			03/28/01	
ME		09/819,692		Okoroanyanwu et al			03/28/01	
ME		6,107,172	08/22/00	Yang et al	438	585		
ME		6,103,457	08/15/00	Gabriel	430	318		
ME		5,965,481	10/12/99	Yang et al	438	717		
ME		5,003,178	03/26/91	Livesay	250	492.300		
FOREIGN PATENT DOCUMENTS								
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB- CLASS	TRANSLATION	
							YES	NO
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)								
ME		Livesay, W. R., "Large-area electron-beam source," Journal of Vacuum Science & Technology B, Vol. 11, No. 6, Nov/Dec. 1993, pp. 2304-2308, American Vacuum Society						
ME		Yang, J. J. et al, "Electron Beam Processing for Spin-on Polymers and Its Applications to Back-End-of-Line (BEOL) Integration," Materials Research Society Symposium Proceedings, Vol. 511, 1998, pp. 49-55, Materials Research Society						
ME		Ross et al, "Plasma Etch Characteristics of Electron Beam Processed Photoresist," The Society of Photo-Optical Instrumentation Engineers, Vol. 2438, 1995, pp. 803-816, SPIE-The International Society for Optical Engineering						
ME		Grün, Von A. E., "Lumineszenz-photometrische Messungen der Energieabsorption im Strahlungsfeld von Elektronenquellen Eindimensionaler Fall in Luft," Zeitschrift für Naturforschung, Vol. 12a, 1957, pp. 89-95, Publisher: Zeitschrift für Naturforschung; full English Translation attached (11 pgs.)						
EXAMINER M. El-Shammaa				DATE CONSIDERED 3.31.04				
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